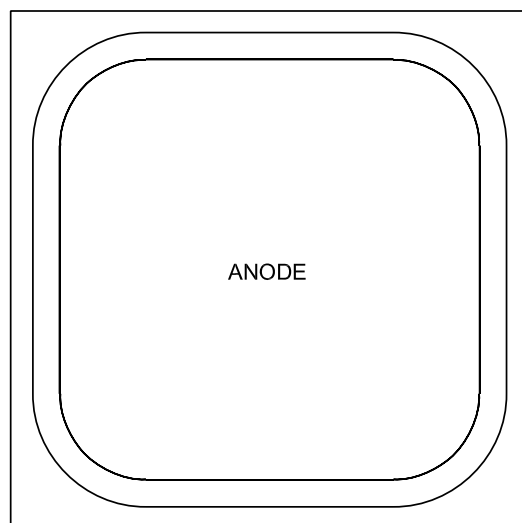


PROCESS DETAILS

| | |
|------------------------|-----------------------------------|
| Process | EPITAXIAL PLANAR |
| Die Size | 61 x 61 MILS |
| Die Thickness | 9.8 MILS |
| Anode Bonding Pad Area | 55 x 55 MILS |
| Top Side Metalization | Ti/Ag - (2,500Å/30,000Å) |
| Back Side Metalization | Ti/Ni/Au - (1,600Å/5,550Å/1,500Å) |

GEOMETRY



BACKSIDE COLLECTOR

R0

GROSS DIE PER 4 INCH WAFER

3,118

PRINCIPAL DEVICE TYPES

CTLSH3-30M833

145 Adams Avenue
Hauppauge, NY 11788 USA
Tel: (631) 435-1110
Fax: (631) 435-1824
www.centrasemi.com

R0 (02 -March 2006)